## IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant: Chun-Lien Su et al

Attorney Docket No.: 4006-150

Serial No.: 10/054,962

Group Art Unit:

1765

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Examiner:

Chen, Kin Chan

Title:

METHOD FOR CONTROLLING AND MONITORING

CHEMICAL MECHANICAL POLISHING PROCESS

## **AMENDMENT**

Commissioner for Patents P.O. Box 1450 Alexandria, VA 22313-1450 PROCEINED TO 1200

Dear Sir:

This paper is in response to the Official Action mailed June 24, 2003. Applicants respectfully submit the following amendments and comments in connection with the above-named application.